



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re the Application of: **HATTORI, Kazuhiro**

Serial No.: 09/816,784

Filed: March 26, 2001

Group Art Unit: 1765

Examiner: **Lan Vinh**

P.T.O. Confirmation No.: 5542

For: **DRY ETCHING METHOD, MICROFABRICATION PROCESS AND DRY ETCHING MASK**

RESPONSE UNDER 37 CFR §1.116

- EXPEDITED RESPONSE -
GROUP ART UNIT 1765

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 22, 2004

Sir:

In response to the Office Action dated **October 22, 2003**, please amend the above-identified application as follows:

RECEIVED
JAN 26 2004
TC 1700

AF
OK to enter
LV
2/5/2004